INCLINATION SENSOR

Inclination Sensor in MEMS Technology







CHARACTERISTICS



ADVANTAGES

MEMS technology

High protection level IP67 and wide temperature range from -40°C ... +85°C

Stable accuracy over whole temperature range

Resolution up to 0,01°

Single axis 0° to 360° or ±180°

Double axes \pm 1° to \pm 60°

Instantaneous Gyro-compensated measure

Excellent accuracy

Reliability and long service life for outdoor applications

Very compact dimensions

High shock/vibration resistance



High protection



Shock/vibration resistant



Reverse polarity protection



Wide range temperature



MEMS sensors technology



Ana**l**og output



Horizontal version



Vertical version



High accuracy



High repeatability



Directive 2011/65/EU



EU conformity

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PRODUCT DESCRIPTION

TLP300 is available with one or two measurement axes. The inclinometer working principle is based on a micro machined silicon capacitive transductor (developed with MEMS technology).

Utilizing gyro-compensated MEMS technology, the sensor position signal is instantaneous with no delays and has a static excellent linearity.

TLP300 is suited for applications (cranes, aerial platforms, drilling machines and excavators) in harsh environments which are exposed to motion, shock and vibration, especially for mobile machines.















Version output

= Single

S

R

a	Power supply
2	= 9 30 V DC (STD)
3 •	= 12 30 V DC (only for outputs 4; 7)

6		Measurement direction
0	4	= Dual axes
V	4	= Single axis (for 0XXX° version)
V1	4	= Single axis (for ±XXX° version)

G	Range
XXX <	= FS angle deg for single axis*
XXX ◀ = ± angle deg. for double axes**	

d	Output	
2 4	= 0,5 4,5 V DC	
3 4	= 0 5 V DC	
4 •	= 0 10 V DC	
7	= 4 20 mA	
7	= 4 20 mA	

Type of connection= Male connector M12x5, PUR cable 30		Type of connection
		= Male connector M12x5, PUR cable 30cm
2	2 = Male flange connector 1xM12, 5-pin	

9	Version output
0 •	= Static (without gyro-compensated)
1 •	= Dynamic (with gyro-compensated)

 $= Redundant \ (only \ for \ vertical \ versions)^{***}$

- * = value for O = 050 (\pm 50°); V = 090 (0 ... 90°); V1 = 040 (\pm 40°)
- ** = value of 010 means range $\pm 10^{\circ}$

2

*** = Output Z1 = CW & Output Z2 = CCW

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TECHNICAL SPECIFICATION

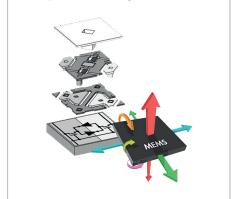
$\pm 1^{\circ}$ to $\pm 60^{\circ}$ for horizontal version 0° to 360° for vertical version or $\pm 180^{\circ}$	
< ±0,3°	
0.01°	
0,01 °/°C	
IP67	
-40°C +85°C [-40°F+185°F]	
PA6 + GF30%	
<0,3 s after power on	
approx. 100 g [3.53 oz]	
acc. to EN 60068-2-27 30 G, 11 ms	
acc. to EN 60068-2-6 10 500 Hz	



OPERATING PRINCIPLE

Operating principle

MEMS (acronym for Micro Electro Mechanical Systems) technology enables both electronic circuits and opto-mechanical devices to incorporate on the same silicon substrate, using manufacturing technologies similar to those used for the implementation of integrated circuits.

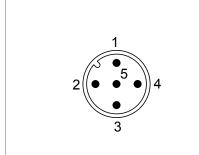




ELECTRICAL CHARACTERISTICS

Power supply	9 30 V DC (STD) see more detail on order code	
Reverse polarity protection	YES	
Electromagnetic compatibility	acc. to EN 61326-1, EN 61326-3-1	
CE compliant	acc. to EMC guideline 2014/30/EU RoHS guideline 2011/65/EU	

ANALOG ELECTRICAL CONNECTION M12 X 5 PINS



Pinout

	Single axis	Dual axes
1	+Vin	+Vin
2	V / I out Z 2*	V / I out Y
3	GND	GND
4	V / I out Z 1	V / I out X
5	zero input**	zero input**

- * = ONLY FOR REDUNDANT VERTICAL VERSIONS IN OTHER CASES SHOULD NOT BE CONNECTED
- ** = CONNECT TO GND FOR TWO SECONDS IN ORDER TO HAVE OFFSET

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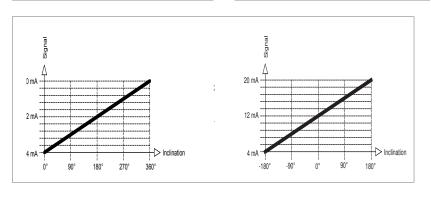


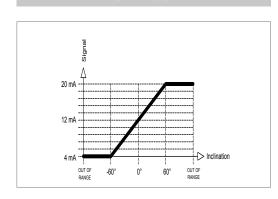


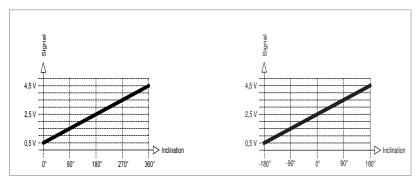
V1 = ±180°

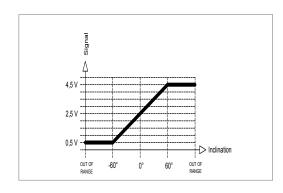
Dual axes

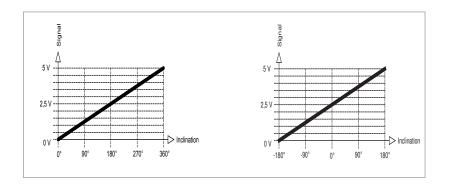
 $O = \pm 60^{\circ}$

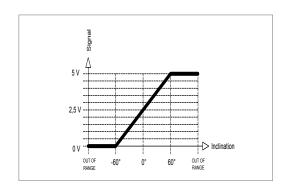


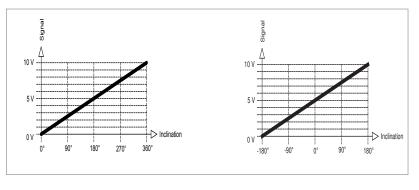


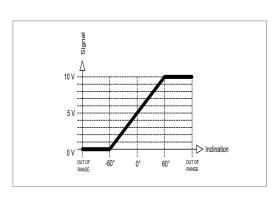












DATASHEET - Rev.3 - 09012019

TLP300 INCLINATION SENSOR

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Dual axes



TSM dual axes TLP300 inclination sensor

The 2-dimensional inclination sensor must be mounted with the base plate in horizontal position, i.e. parallel to the horizontal line.

The sensor can be inclined both towards the X and Y axis at the same time. For each axis a separate measured value is provided.









Single axis



TSM single axis TLP300 inclination sensor

The 1-dimensional inclination sensor must be installed with its Z-axis in line with the force of gravity, as illustrated below.

The 1-dimensional sensor defaul t position is 0° as shown in the following illustration.

V (0...360°)





V1 (± 180°)





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